



Practitioner's Docket No. 081468-0307473
Client Reference: P-1795.000-US

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **VADIM YEVGENYEVICH BANINE et al.**

Application No.: 10/748,851

Confirmation No.: 2813

Filed: December 31, 2003

Group No.: 2851

Examiner:

For: **LITHOGRAPHIC APPARATUS HAVING A DEBRIS-MITIGATION SYSTEM,
A SOURCE FOR PRODUCING EUV RADIATION HAVING A DEBRIS MITIGATION
SYSTEM AND A METHOD FOR MITIGATING DEBRIS**

**Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**

**SUPPLEMENTAL APPLICATION DATA SHEET
37 C.F.R. § 1.76(c)**

The following information on the Application Data Sheet is changed as indicated:

BIBLIOGRAPHIC DATA

1. Applicant information is being modified.

| | |
|------------------------|---|
| SIXTH applicant | <u>ABRAHAM VEEFKIND</u> |
| Citizenship | <u>Dutch</u> |
| Residence | <u>Willem Alexanderpark 17, NL-2202 XW Noordwijk, The Netherlands</u> |

2. Assignee information is being added.

The assignee of this application is:

**ASML NETHERLANDS B.V.
De Run 6501, NL-5504 DR Veldhoven, The Netherlands
Extent of interest of assignee in application: ENTIRE RIGHT, TITLE AND INTEREST**

Date: July 1, 2004

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Signature of Practitioner
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